

Starspheric

薄膜涂层测厚仪 >>

星弧涂层薄膜涂层测厚仪-Starspheric-02是一款可用于各种薄膜和涂层厚度的测量仪器，所测量的涂层不受成份、硬度等各种因素的限制。它的操作简单，维护成本较其它类型的测厚仪更低。

Starsphenc-02膜厚测量原理是通过磨球在膜层上磨制成球面并测量球面的半径从而计算出膜层的厚度。测厚仪由球磨机构、高倍显微镜、微电脑及测试软件组成。

Starspheric-02 provides quick, simple and inexpensive measurement of coating thickness. The measurement is not affected by coating spices and hardness. A roating sphere with a specific diameter sits on the coating surface. Upon adding abrasive slurry to the contact point, an impression with the shape of a spherical cap is abraded into both the coating and the substrate. By measuring the parameters X and Y, the thickness of the coating D can be calculated by a simple geometrical equation.

功能和技术特性-Functions and Specifications

- 测量厚度 (Thickness range) : >100nm
- 实用膜层 (Coating species) :各种单一和复合膜层 (monolayer and multilayer), 如类金刚石DLC (DLC coating) TiX等硬涂层(Hard coatings like TiN,TiCN,TiX,etc.)、SiN和SiO₂、陶瓷或电镀涂层 (Ceramic and electro plating)
- 中文测量软件界面 (User friend interface)
- 尺寸 (Dimension) : 450X400mm
- 其他功能 (Other function) : 膜层耐磨性 (Coating wear resistance)

测厚仪主要部件-Key Components

- 球磨机构 (Rotation sphere mechanism)
- 高倍测量显微镜(350倍) (Microscope with 350X magnification)
- 微电脑及中文界面的测量软件 (Microcomputer with measuring software)

测厚原理-Measuring Principle

